

## **IN THE CLAIMS**

Kindly **REPLACE** claims 1 and 9 with the following:

1. A silicon refining method comprising the steps of:  
filling an unlined inductive crucible (1) with solid silicon;  
melting the content of the crucible;  
creating, by means of the inductive crucible, a turbulent stirring of the silicon melt (b) by  
bringing the liquid from the bottom of the crucible to the free surface by ascending along  
the central axis of the crucible; and  
directing a plasma (f) generating by an inductive plasma torch (2) towards the melt  
surface for a duration enabling elimination of impurities for which the reactive gas ( $g_r$ ) of the  
plasma is adapted.
  
9. A silicon refining installation comprising:  
an unlined inductive crucible (1) adapted to receiving the silicon;  
an inductive plasma torch (2) directed towards the free surface of the silicon load  
contained in the crucible; and  
a removable magnetic yoke (3) between the plasma torch (2) and the crucible (1) for  
inverting a stirring direction of the silicon load, the yoke being ring-sharped to enable the passing  
of the plasma flame (f).